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## PATENT ABSTRACTS OF JAPAN

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(71)Applicant: KURITA WATER IND LTD

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(72)Inventor: NISHIKAWA SHOZO

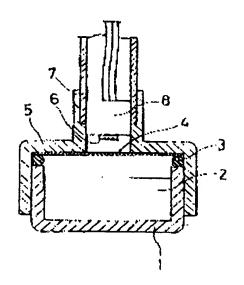
SAKAI AKISHIRO 

## (54) DETECTION OF MICROORGANISM

#### (57)Abstract:

PURPOSE: To make detection of microorganisms possible by a simple device and operation, by detecting a gas evolved by cultivation by a gas sensor, measuring time from beginning of cultivation to the detection of gas.

CONSTITUTION: In a detector having the container 1 storing the culture 2, the cover 5 having the opening part 6 at least one part, and the gas sensor 8 inserted into the opening part 6, a test specimen is added to a medium, cultivation is carried out, a gas evolved by the cultivation is detected by the gas sensor 8, and microorganisms are detected from time from beginning of the cultivation to the detection of gas. Namely, the microorganisms can be detected by a simple device and operation in a short time without using a specific reagent except the medium. Since a gas can be detected by a gas sensor, and immersion of the gas sensor in a liquid is not required, neither the sensor is contaminated nor various germs are added to the medium, and microorganisms can be accurately detected.



## LEGAL STATUS

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